

10/562158

Docket No.: 4684-030

JC10 Rec'd PCT/PTO 23 DEC 2005 <sup>PATENT</sup>

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kang-Ho AHN

U.S. Patent Application No.: -----

Filed: *herewith*

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Confirmation No.

Group Art Unit: -----

For: APPARATUS FOR CONTROLLING FLOW RATE OF GASES USED IN  
SEMICONDUCTOR DEVICE BY DIFFERENTIAL PRESSURE

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Preliminary to examination of the above-referenced application, please amend the application as follows: